

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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| In re Patent Application of: |) Confirmation No.: 3788 |
| Shinji MAEKAWA et al. |) Examiner: Stanetta D. Isaac |
| Application No.: 10/575,492 |) Group Art Unit: 2812 |
| Filed: April 12, 2006 |) |
| For: METHOD FOR FORMING WIRING, METHOD |) |
| FOR MANUFACTURING THIN FILM |) |
| TRANSISTOR AND DROPLET DISCHARGING |) Date: <u>January 4, 2010</u> |
| METHOD |) |

RESPONSE TO FINAL OFFICE ACTION

Mail Stop: RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated October 5, 2009, Applicants respectfully request reconsideration and allowance of the above-identified application based on the following amendments and remarks. A request for continued examination under 37 C.F.R. § 1.114, including the fee set forth by 37 C.F.R. § 1.17(e), is being filed concurrently herewith, for entry and consideration of the following amendments and remarks.